

<b>Notice of References Cited</b>		Application/Control No. 10/589,399	Applicant(s)/Patent Under Reexamination LU ET AL.	
		Examiner YOSHITOSHI TAKEUCHI	Art Unit 1793	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
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**FOREIGN PATENT DOCUMENTS**

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	N					
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	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Yan et al, Microstructure of Surface Layers in Cu(In,Ga)Se <sub>2</sub> Thin Films, NREL/CP-520-33615 (May 2003).
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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